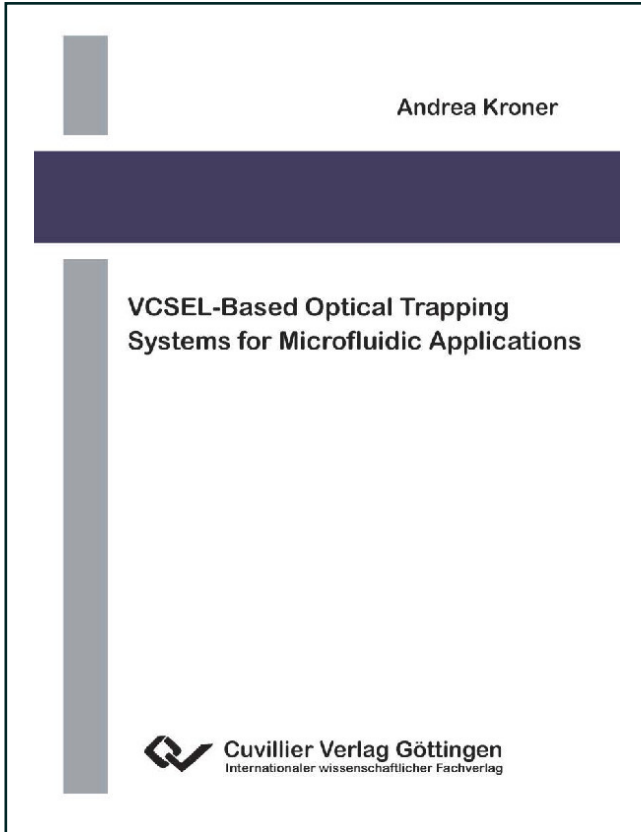




Andrea Kroner (Autor)

## **VCSEL-Based Optical Trapping Systems for Microfluidic Applications**



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